

1960.30 DIV. I

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
TIMOTHY M. RICHARDSON ) : Examiner: R. Ratliff  
Application No.: NYA ) : Group Art Unit: 2877  
Filed: February 2, 2001 ) :  
For: TEST SLIDE FOR ) February 2, 2001  
MICROSCOPES AND METHOD ) :  
FOR THE PRODUCTION OF ) :  
SUCH A SLIDE ) :

jc841 U.S. PTO  
09/773674  
02/02/01



Commissioner for Patents  
Washington, D.C. 20231

[This application is a divisional of  
Appln. No. 08/882,491, filed  
June 25, 1997, now allowed]

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under  
37 C.F.R. § 1.56 and in accordance with the practice under  
37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is  
directed to the documents listed on the enclosed Form  
PTO-1449. Copies of the listed documents are also enclosed.

CONCLUSION

It is respectfully requested that the below-listed information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 625-3500. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

  
\_\_\_\_\_  
Attorney for Applicant  
Registration No. 31,588

PATENT ADMINISTRATOR  
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09/73674  
02/02/01



Date Submitted to PTO: February 2, 2001

## U.S. PATENT DOCUMENTS

| *EXAMINER INITIAL | DOCUMENT NUMBER | DATE  | NAME               | CLASS | SUBCLAS S | FILING DATE IF APPROPRIATE |
|-------------------|-----------------|-------|--------------------|-------|-----------|----------------------------|
|                   | 4,055,376       | 10/77 | Daberko            | 350   | 10        |                            |
|                   | 5,622,796       | 4/97  | Canestrari, et al. | 430   | 22        |                            |
|                   | 4,616,241       | 10/86 | Biefeld, et al.    | 357   | 16        |                            |
|                   | 4,947,223       | 8/90  | Biefeld, et al.    | 357   | 30        |                            |
|                   | 5,027,178       | 6/91  | Svilans            | 357   | 30        |                            |
|                   | 5,608,519       | 3/97  | Gourley, et al.    | 356   | 318       |                            |
|                   |                 |       |                    |       |           |                            |

## FOREIGN PATENT DOCUMENTS

|  | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLAS S | TRANSLATION YES/NO/ OR ABSTRACT |
|--|-----------------|------|---------|-------|-----------|---------------------------------|
|  | 0,214,1601      | 5/90 | Europe  | G01B  | 7/34      | Abstract                        |
|  | 2,702,277       | 9/94 | France  | G01M  | 11/00     |                                 |
|  |                 |      |         |       |           |                                 |
|  |                 |      |         |       |           |                                 |
|  |                 |      |         |       |           |                                 |

## OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER

DATE CONSIDERED

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 2

Date Submitted to PTO: **February 2, 2001**PTO  
1C841 U.S. 11367A  
02/01

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

**Electro-Optical Systems Design; OTF Quantitative Image Analysis; David Smith, Dec. 1979.****Cambridge University Press; Nanofabrication And Biosystems, H. Hoch, L.W. Jelinski, and H.G. Craighead.****Development In Semiconductor Microlithography; Testing The Mann Type 4800DSW™ Wafer Stepper™, W. Schneider, vol. 174, pp. 6-14 (1979)****JENOPTIK, Laser Optik Systeme****“Contrast Transfer In Confocal Microscopy” by R. Oldenbourg, et al.**

EXAMINER

DATE CONSIDERED

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Include copy of this form with next communication to applicant.

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